

# Optical and Electrical Properties of $(\text{SnO}_2)_x(\text{In}_2\text{O}_3)_{1-x}$ thin Films Prepared by Pulse Laser Deposition Technique

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**Abstract** In this work, fundamental wavelength (1064 nm) Q- switched Nd:YAG laser with 800 mJ peak energy on  $\text{SnO}_2:\text{In}_2\text{O}_3$  target to produce ITO thin films. Thin films characterized by UV-visible absorbance, DC conductivity, Hall effect measurements and X-ray diffraction. It was found that the transmission increase with increasing  $\text{In}_2\text{O}_3$  ratio from 0 to 0.5 reaching about 88% in visible range. It can be seen that the conductivity increase with increasing ratio from 0 to 0.3 then decrease at 0.5 ratio. It can be found from Hall effect measurement that the mobility  $\mu_{\text{H}}$  increase at 0.1 ratio then decrease with more  $\text{In}_2\text{O}_3$  content.

**Keywords:** ITO, XRD, DC conductivity, UV-visible

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## 1. Introduction

Conducting oxide thin films are being an important component in different optoelectronic devices such as solar cells [1], light emitting diodes [2] and photodiodes devices [3] in which they are used as transparent electrodes. The resistivity of these electrodes should be minimized as much as possible with keeping its high optical transparency particularly over the visible region of the solar spectrum. Indium Tin oxide ITO is a promising material due to its exclusive properties such as high electrical conductivity, high optical transparency for light [4,5].

A transparent electrode is needed in manufacturing of solar cells on the side where light enters. Normally, transparent conductive oxides (TCO) like indium tin oxide (ITO) or zinc oxide (ZnO) are commonly used for such purpose [6].

We need to study the optical and electrical properties for used to reach optimum conditions for preparation ITO films. The unique properties of ITO come from its structure and composition.

One unit cell contains 16 units of  $\text{In}_2\text{O}_3$ . Therefore, for defect free  $\text{In}_2\text{O}_3$  crystal, there are 80 atoms in one unit cell. The lattice constant is reported to be  $10.118\text{\AA}$  [7]. When tin atoms substitute for indium atoms, it forms either SnO or  $\text{SnO}_2$ . If SnO is formed, tin acts as an acceptor since it accepts an electron. Otherwise, when  $\text{SnO}_2$  is formed, it acts as donor. The material retains its bixbyite structure. However, if the doping level is extremely high, the tin atoms may enter interstitially and distort the lattice structure. The high transparency in the

visible wavelength range of 400 - 800 nm was explained by a low concentration of mid-gap states, typically responsible for absorption of photons with energies below the band-gap energy [8].

As the tin concentration increases, the carrier concentration increases until a saturation level is reached. An increase in the tin concentration above this saturation level causes a decrease in the free carrier concentration. ITO has metal like electrical properties because the carrier concentration is typically around  $10^{20}$  to  $10^{21}\text{cm}^{-3}$ .

X-ray diffraction Bragg's law was used to calculate inter-plane distance for crystals ( $d_{\text{hkl}}$ ) from the condition of X-ray diffracted interference from parallel planes [9]

$$n \lambda = 2 d_{\text{hkl}} \sin \theta \quad (1)$$

where  $\theta$  is diffraction angle and  $\lambda$  is the used XRD wavelength.

The x-ray diffraction peaks broadening is used to calculate crystalline size by Scherrer equation formula [10].

$$G.S = \frac{0.9\lambda}{FWHM \cdot \cos(\theta)} \quad (2)$$

Where  $\lambda$  is the used x-ray wavelength, FWHM is full width at half maximum (in radians) and  $\theta$  is diffraction angle.

## 2. Experimental Part

Stannic oxide ( $\text{SnO}_2$ ) purity (99.98 %) powder by FERAK, England Company and Indium (III) oxide

( $\text{In}_2\text{O}_3$ ), with purity (99.9 %) by Hi Media Laboratories Pvt.Ltd. (India) of these materials were mixed, with different  $\text{In}_2\text{O}_3$ : $\text{SnO}_2$  ratio (0, 10, 30 and 50) % in gate mortar to use it to make target as a disk of 1.5cm diameter and 0.3cm thickness using hydraulic piston type (SPECAC), under pressure of 6 tons for 10 minutes

$\text{SnO}_2$ ,  $\text{In}_2\text{O}_3$  and  $\text{SnO}_2$ :  $\text{In}_2\text{O}_3$  thin films were prepared by Q switched pulsed laser laser (Huafei Tongda Technology- DIAMOND-288 pattern EPLS)  $\lambda = 1064 \text{ nm}$  with 800 mJ peak power inside a vacuum chamber at vacuum ( $10^{-3}$  Torr) using double stage rotary pump. Pulsed laser used to growth thin film by interaction of the pulsed laser beam with a target formed laser-induced plasma used to deposit thin films on glass substrates at low pressure. The set-up of laser deposition chamber photograph is given in Figure 1. The focused Nd:YAG SHG Q-switching laser incident beam coming through a window is making an angle of  $45^\circ$  with the target surface. The substrate is placed parallel in front of the surface of the target.

The produced films were characterized by X-ray

diffraction (XRD), Dc conductivity, Hall effect measurements and UV-visible absorption to study the effect of  $\text{In}_2\text{O}_3$ : $\text{SnO}_2$  ratio on produced thin films properties.

### 3. Results and Discussion

Figure 2 displays X- ray diffraction for  $\text{In}_2\text{O}_3$ : $\text{SnO}_2$  composite with different ratio deposited on glass substrate and annealed at 773 K. The pure sample pattern have four peaks located at  $2\theta$  about  $26.5201$ ,  $33.8462$ ,  $37.9487$  and  $51.7216^\circ$  corresponding to (110), (101), (200) and (211) direction respect to  $\text{SnO}_2$  crystals. It can be seen that these peaks vanished gradually with increasing  $\text{In}_2\text{O}_3$  ratio with appearance of  $\text{In}_2\text{O}_3$  peaks with high degree of crystallinity. The full width of half maximum (FWHM) for observed peaks increase with increasing ratio, i.e decreasing the crystalline size with increasing. Table 1 shows all peaks observed in XRD and a comparison with standard peaks.

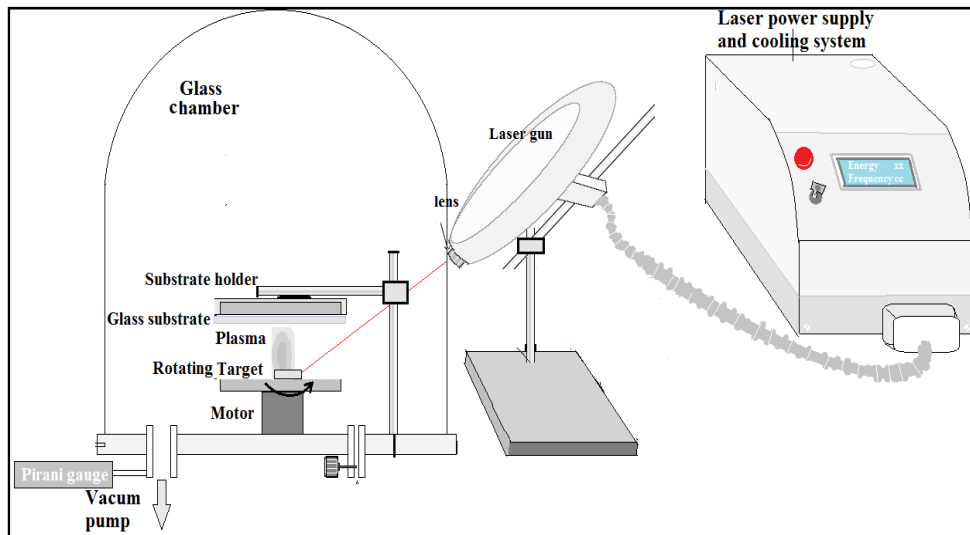


Figure 1. Schematic for pulse laser deposition experimental set up

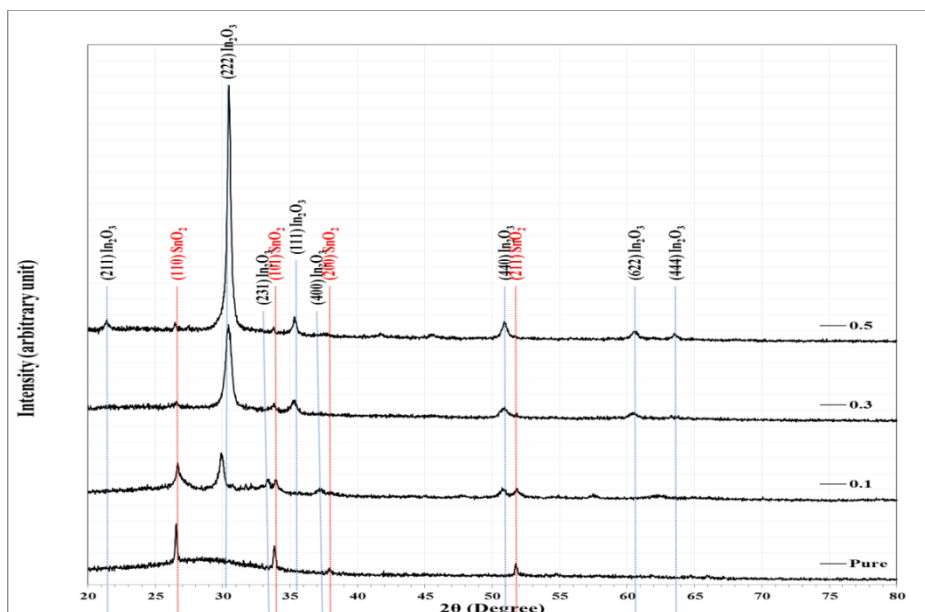


Figure 2. XRD patterns for samples produced by 800 mJ laser using different  $\text{In}_2\text{O}_3$ : $\text{SnO}_2$  ratio

Table 1. comparison between experimental and standard XRD peak and calculated crystalline size

Ratio	2 $\theta$ (Deg.)	FWHM (Deg.)	d <sub>hkl</sub> Exp.(Å)	G.S (nm)	hkl	d <sub>hkl</sub> Std.(Å)	Phase	Card No.
	26.5201	0.2150	3.3583	38.0	(110)	3.3498	SnO <sub>2</sub>	96-210-4744
<b>Pure</b>	33.8462	0.2170	2.6463	38.3	(101)	2.6439	SnO <sub>2</sub>	96-210-4744
	37.9487	0.4395	2.3691	19.1	(200)	2.3686	SnO <sub>2</sub>	96-210-4744
	51.7216	0.2930	1.7660	30.1	(211)	1.7642	SnO <sub>2</sub>	96-210-4744
	26.6667	0.6593	3.3402	12.4	(110)	3.3498	SnO <sub>2</sub>	96-210-4744
	29.8901	0.4396	2.9869	18.7	(222)	2.9214	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	33.4066	0.2930	2.6801	28.3	(231)	2.7047	In <sub>2</sub> O <sub>3</sub>	96-101-0589
<b>0.1</b>	33.9194	0.2197	2.6407	37.8	(101)	2.6439	SnO <sub>2</sub>	96-210-4744
	37.1429	0.5861	2.4186	14.3	(400)	2.5300	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	38.0220	0.4395	2.3647	19.1	(200)	2.3686	SnO <sub>2</sub>	96-210-4744
	50.7692	0.5128	1.7969	17.2	(440)	1.7890	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	51.7949	0.5128	1.7637	17.2	(211)	1.7642	SnO <sub>2</sub>	96-210-4744
	26.5043	0.5116	3.3603	16.0	(110)	3.3498	SnO <sub>2</sub>	96-210-4744
	30.3776	0.4385	2.9401	18.8	(222)	2.9214	In <sub>2</sub> O <sub>3</sub>	96-101-0589
<b>0.3</b>	33.7393	0.4385	2.6544	18.9	(101)	2.6439	SnO <sub>2</sub>	96-210-4744
	35.3471	0.4385	2.5373	19.0	(400)	2.5300	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	50.8404	0.8039	1.7945	10.9	(440)	1.7890	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	60.4872	0.6577	1.5294	14.0	(622)	1.5256	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	21.4706	0.4412	4.1354	18.3	(211)	4.1315	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	30.5147	0.2206	2.9272	37.3	(222)	2.9214	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	35.3676	0.3676	2.5359	22.7	(400)	2.5300	In <sub>2</sub> O <sub>3</sub>	96-101-0589
<b>0.5</b>	41.6912	0.3677	2.1647	23.1	(323)	2.1576	In <sub>2</sub> O <sub>3</sub>	96-101-0590
	45.5882	0.4412	1.9883	19.5	(341)	1.9847	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	50.8824	0.5147	1.7931	17.1	(440)	1.7890	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	60.5147	0.5148	1.5287	17.9	(622)	1.5256	In <sub>2</sub> O <sub>3</sub>	96-101-0589
	63.5294	0.5147	1.4632	18.2	(444)	1.4607	In <sub>2</sub> O <sub>3</sub>	96-101-0590

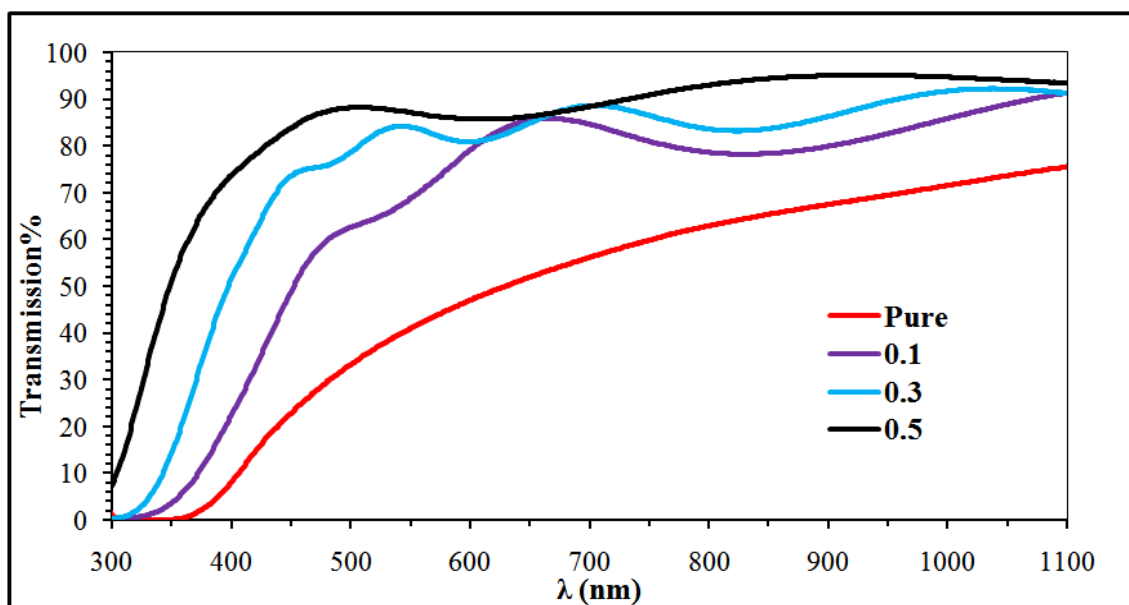
Figure 3. Transmission spectra for In<sub>2</sub>O<sub>3</sub>:SnO<sub>2</sub> with different ratio

Figure 3 shows the transmission spectra for In<sub>2</sub>O<sub>3</sub>:SnO<sub>2</sub> with different ratio. The transmission increase at all range with increasing In<sub>2</sub>O<sub>3</sub> ratio reaching about 88% in visible range, as a result of increasing optical energy gap.

The optical energy gap values ( $E_g^{opt}$ ) for In<sub>2</sub>O<sub>3</sub>:SnO<sub>2</sub> composite films, deposited on glass substrate, annealed at

773 K have been determined by using Tauc equation by plotting  $(\alpha h\nu)^2$  versus photon energy. The optical energy gap ( $E_g^{opt}$ ) determined by the extrapolation of the portion at  $(\alpha h\nu)^2 = 0$  as shown in Figure 4. From this figure seems that the energy gap increase from (3.35 to 3.85) eV with increasing In<sub>2</sub>O<sub>3</sub> ratio from 0 to 0.5.

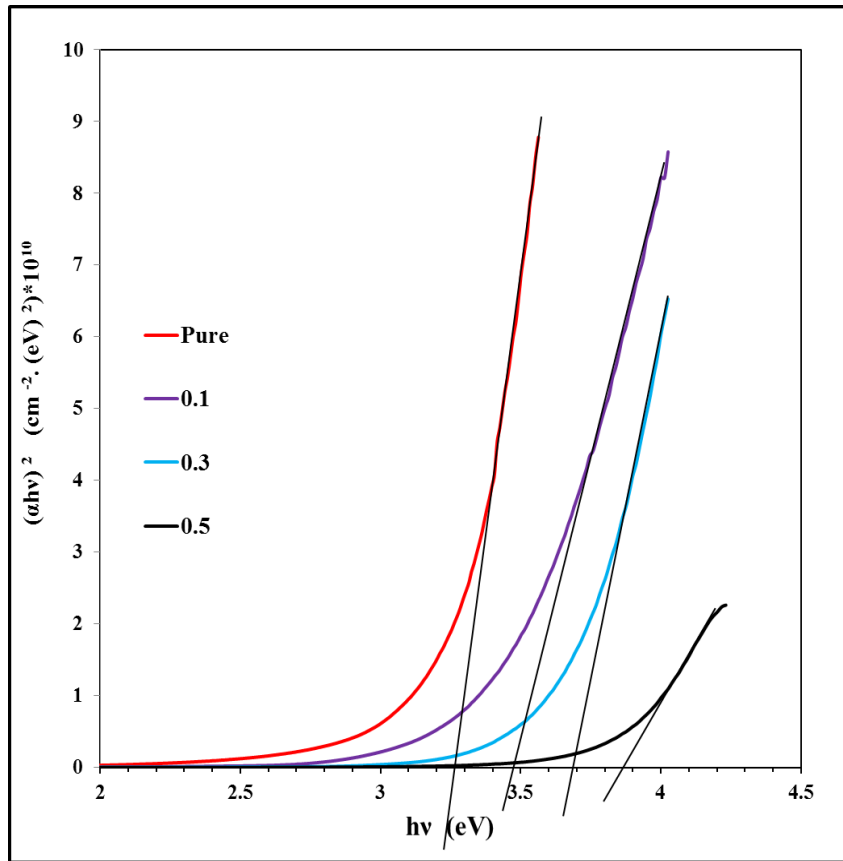


Figure 4. Variation of  $(\alpha hv)^2$  versus photon energy for  $In_2O_3:SnO_2$  thin films with different ratio

The variation of logarithm of DC conductivity with reciprocal temperature for pure  $SnO_2$  films and its composite with  $In_2O_3$  at different ratio (0.1, 0.3 and 0.5) annealed at 773K were carried out in the temperature range (303-473)K as shown in Figure 5.

This figure shows that all films have two activation energies and these activation energies decrease with increasing of  $In_2O_3$  content. All activation energies and

their ranges values have been listed in Table 2. Also it can be seen that the conductivity increase from  $0.9046$  to  $14.8478 \Omega^{-1}.cm^{-1}$  with increasing ratio from 0 to 0.3 then decrease to  $12.0992$  at 0.5. The DC conductivity increase with increasing  $In_2O_3:SnO_2$  ratio due to that (In) ion will act as the donor impurities may occupy shallow donor levels in the film, resulting in the reduction of conduction activation energy [11].

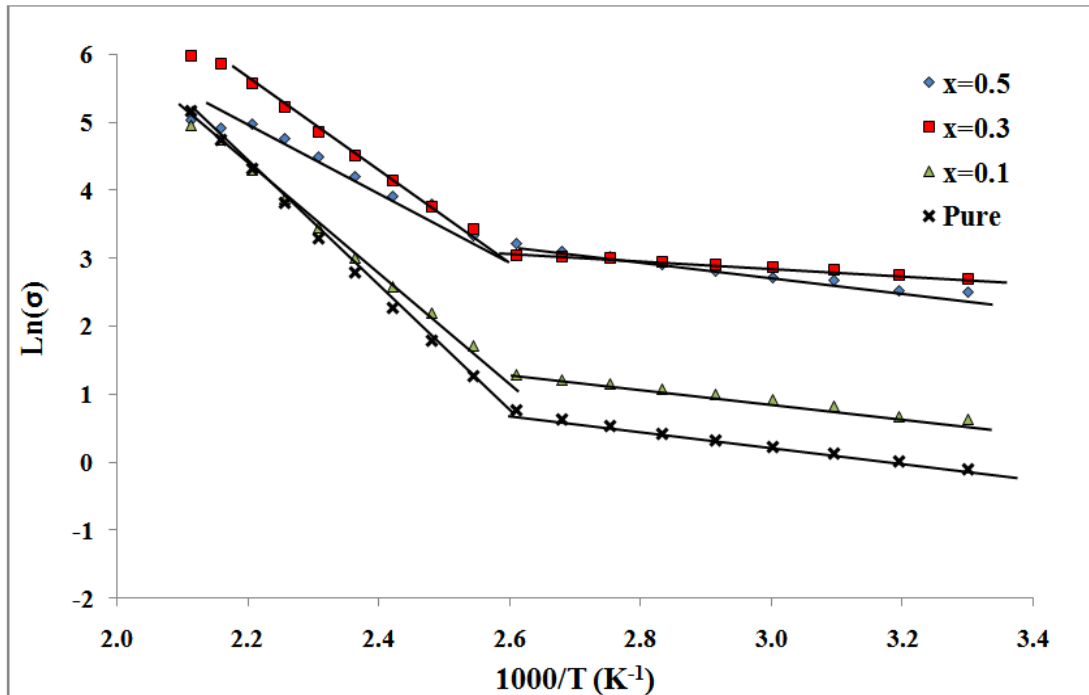
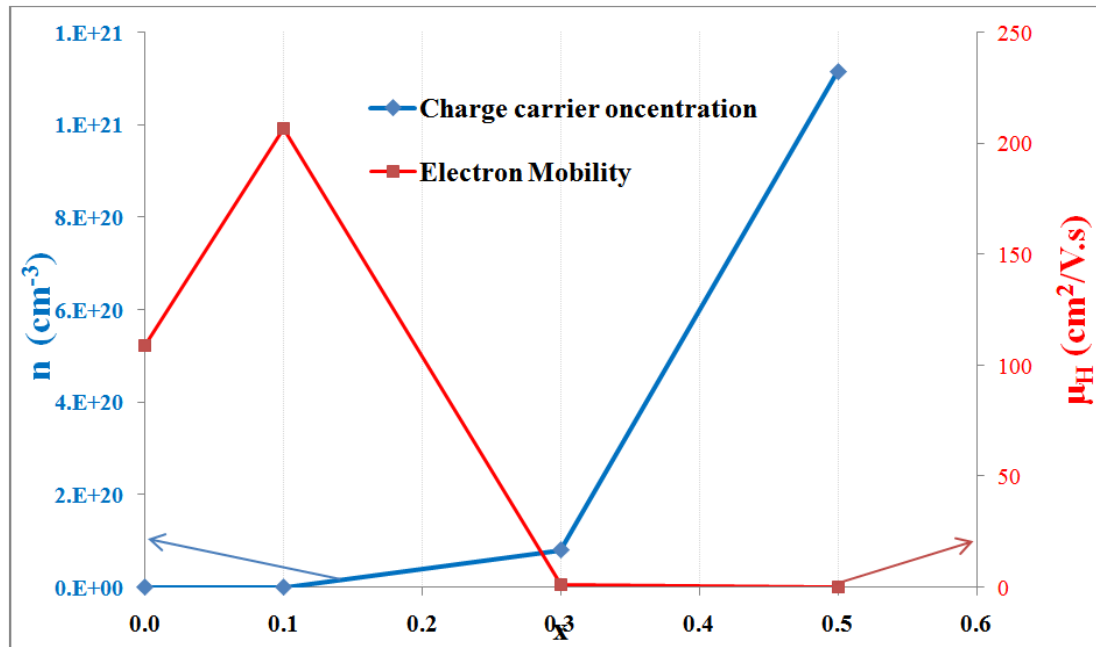


Figure 5. Variation of  $Ln(\sigma)$  with reciprocal temperature for  $In_2O_3:SnO_2$  composite thin films with different ratio

Table 2. DC activation energies, their ranges and conductivity for In<sub>2</sub>O<sub>3</sub>:SnO<sub>2</sub> composite with different ratio

In <sub>2</sub> O <sub>3</sub> :SnO <sub>2</sub>	Ea1 (eV)	Range (K)	Ea2 (eV)	Range (K)	$\sigma RT (\Omega^{-1}.cm^{-1})$
0.0	0.129	303-393	0.792	393-473	0.9046
0.1	0.103	303-393	0.667	393-473	1.8669
0.3	0.061	303-393	0.537	393-473	14.8478
0.5	0.097	303-393	0.346	393-473	12.0992

Figure 6. Variation of carrier concentration (n) and mobility ( $\mu$ ) with dopant ratio

The results obtained from Hall effect show that all films were (n-type). By using of Hall coefficient and films conductivity the charge carrier ( $n_H$ ) and mobility ( $\mu_H$ ) have been calculated. The variation of  $n_H$  and  $\mu_H$  with In<sub>2</sub>O<sub>3</sub>:SnO<sub>2</sub> ratio (x) are shown in Figure 6. It is seen that (n) increases with increasing of In<sub>2</sub>O<sub>3</sub> content to 0.5. Such behavior is expected as a result of the substitution doping of In<sup>3+</sup> creating one extra free carrier in the process. As the doping level is increased, more dopant atoms occupy lattice sites of Sn atoms resulting in more charge carriers, while the mobility  $\mu_H$  increase at 0.1 ratio then decrease with more In<sub>2</sub>O<sub>3</sub> content.

## 4. Conclusions

Transparent, electrically conductive films were obtained with good specifications, with a maximum transmission value of 88% at the visible spectrum. The best samples with In<sub>2</sub>O<sub>3</sub>:SnO<sub>2</sub> ratio equal 0.3, with an electric conductivity of 14.84  $\Omega^{-1}.cm^{-1}$  and with optical transmission up to 80%, while samples with lower or higher ratio in both measurements have lacking in specification.

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